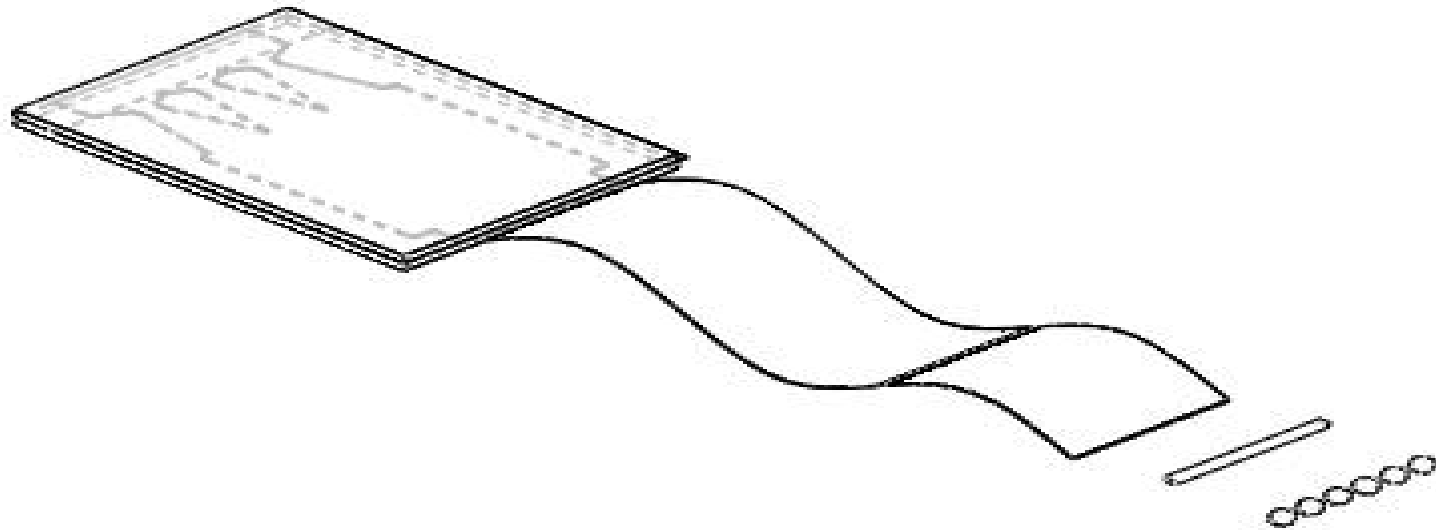


# MEMS Technology for Jet Fuel Atomization

**James Nabity, Sean Rooney**  
TDA Research, Inc



Turbine Engine Technology Symposium 2004  
Fuel-Injector Technology Workshop  
2 September 2004

# Report Documentation Page

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# Outline

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- Objective
- Atomizer technologies
- MEMS atomizer
- Approach to design, build and test
- Conclusions

# Objective

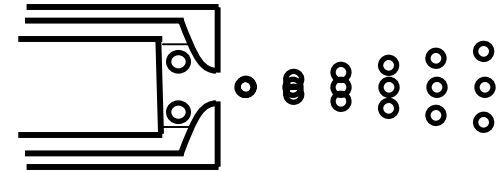
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- Develop a MEMS atomizer to produce small ( $<50\mu\text{m}$ ) droplets
  - improve gas turbine flameholding
  - reduce emissions

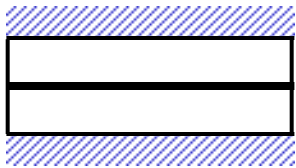
# Baseline Technologies

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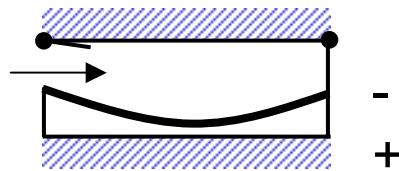
- Air blast / air assist (Many types; internal mixed type shown here)



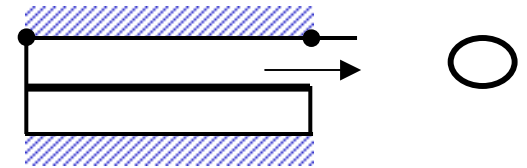
- Others: Simple Orifice, Poppet Orifice, Ultrasonic, Electrostatic Charge, **Inkjet**



Initial state

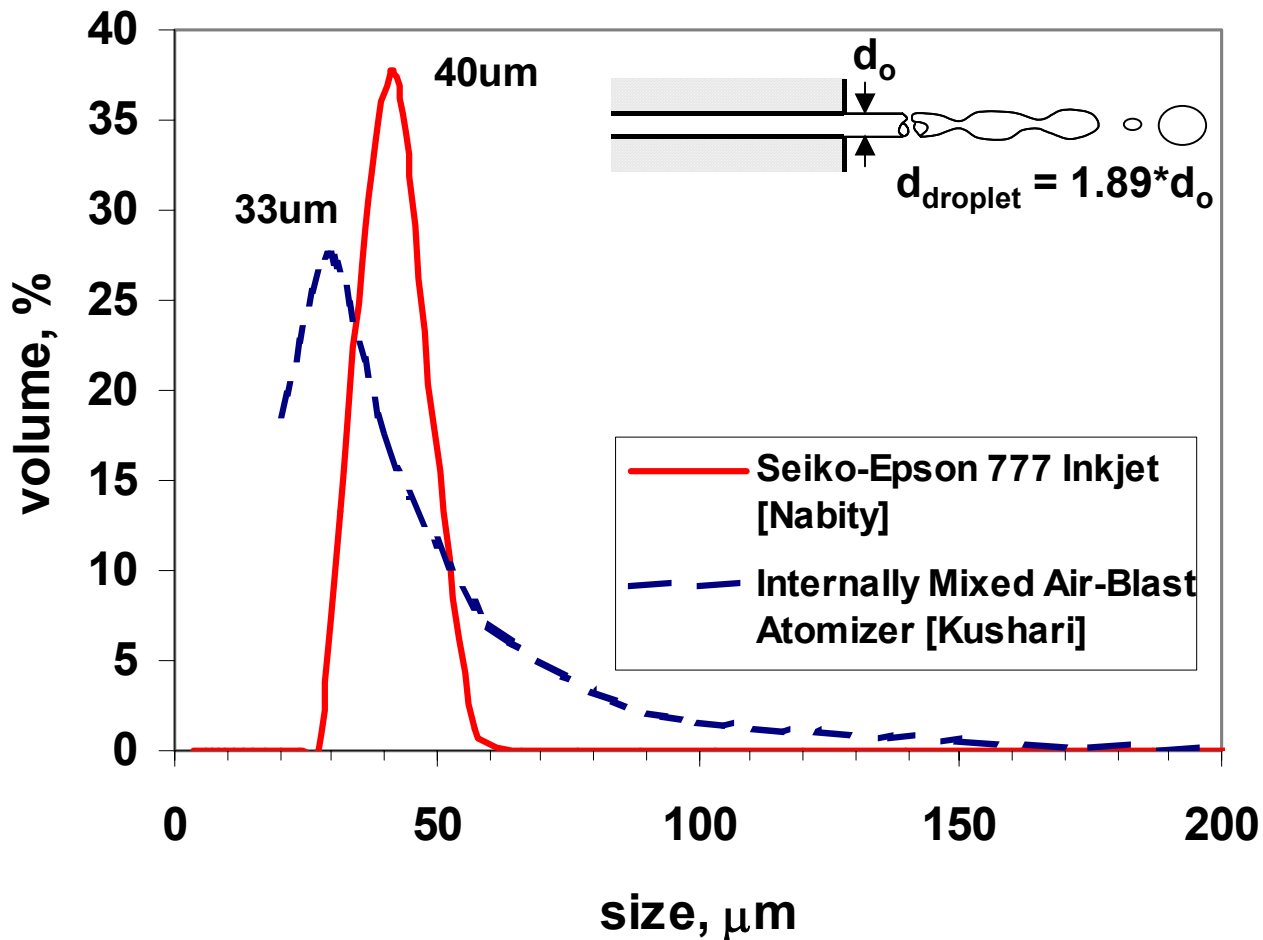


Applied DC voltage draws down the pressure plate or diaphragm



Remove voltage to release diaphragm and eject droplet

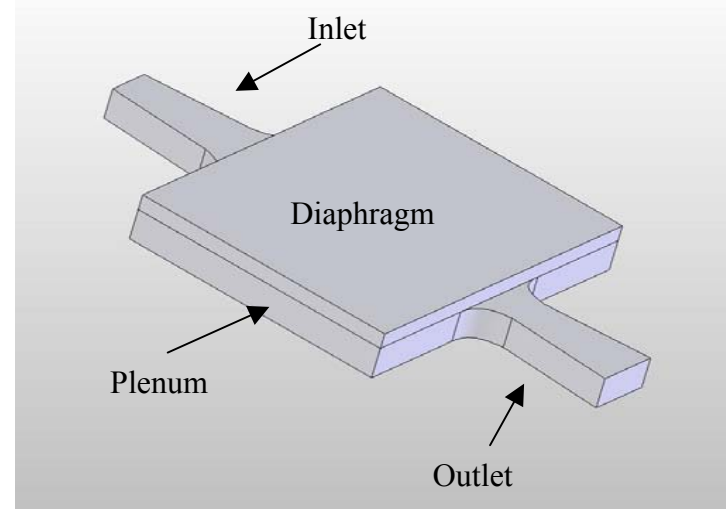
# Droplet Size Measurements



# The Basic Design

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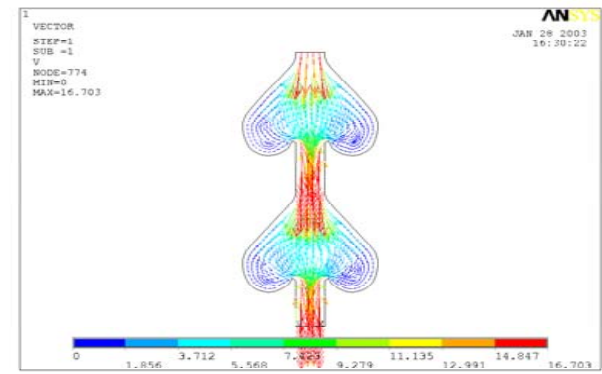
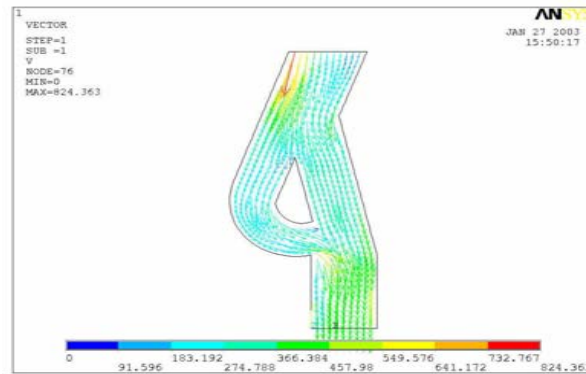
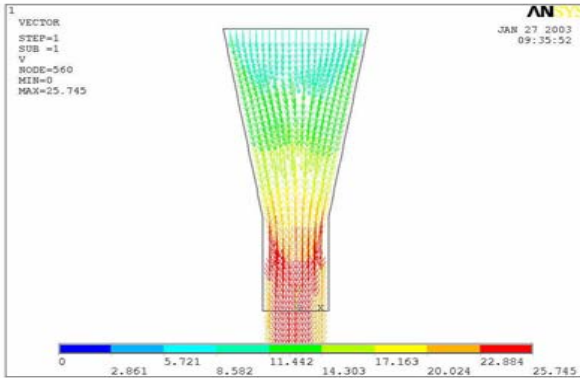
- Electrostatically actuated diaphragm pump with passive valves:
  - Electrostatic for high displacement/low power.
  - Passive valves for simplicity.





# What is Important?

- Need high pump efficiency:  $\eta = \frac{Q_{net}}{Q_{ideal}}$
- Valves are critical



- Dielectric – cleanliness is everything

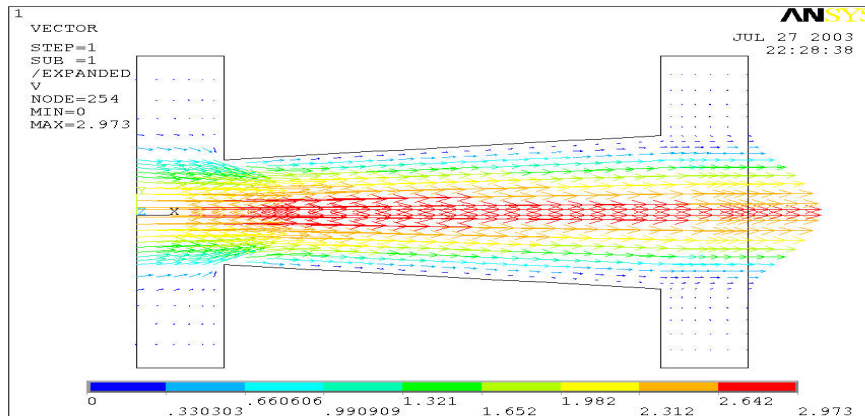
# Approach

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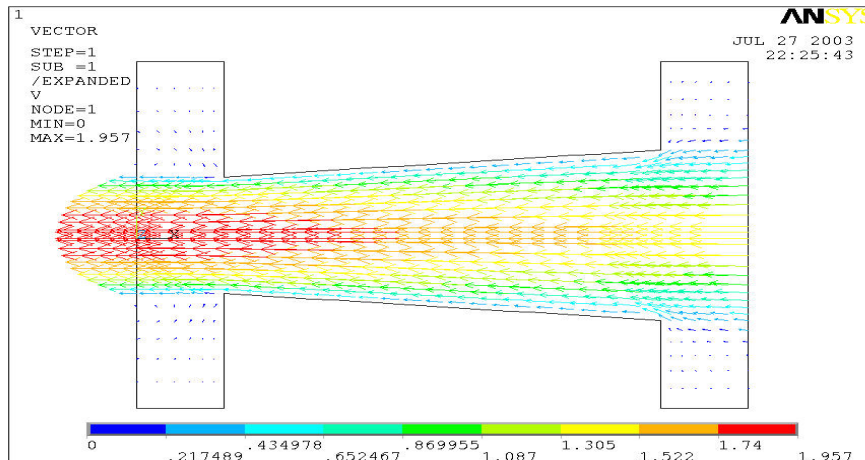
- Analytical & numerical performance modeling
  - Fuel ejection & droplet formation
  - Micropump operation (especially, the valving)
  - Stiction
- Fabrication
  - Materials, processes and assembly
- Engine integration
- Testing

# Fluidic Valve

## Performance Evaluation



forward



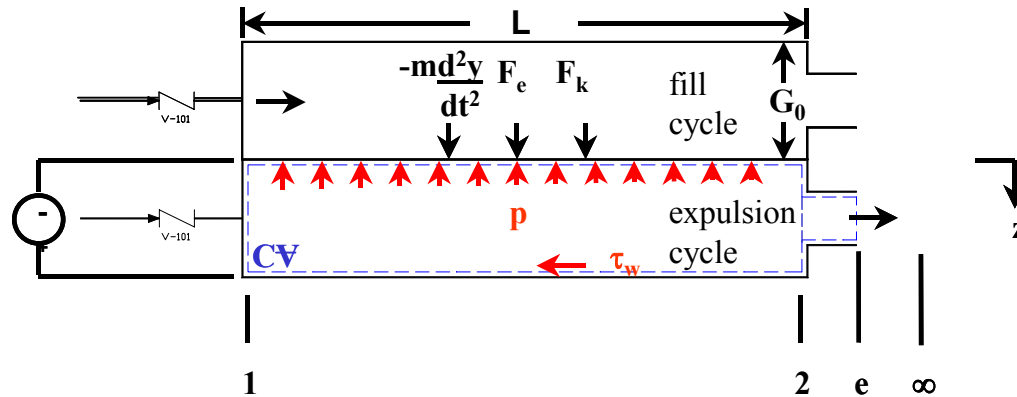
reverse

Flow rectification

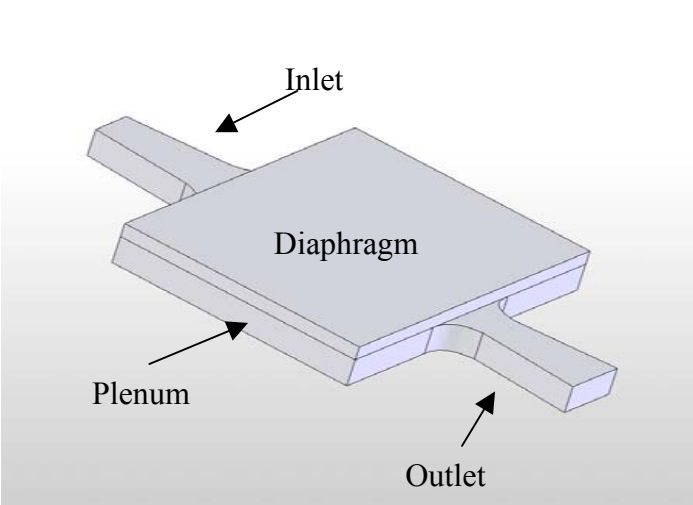
Steady	2.2
Periodic	1.4

# Performance Modeling

- TDA's Quasi 1-D Micropump Model



- ANSYS fully coupled modeling



$$L_{\text{diaph}} = 1000 \mu\text{m}$$

$$t_{\text{diaph}} = 10 \mu\text{m}$$

$$t_{\text{plenum}} = 100 \mu\text{m}$$

$$t_{\text{passages}} = 100 \mu\text{m}$$

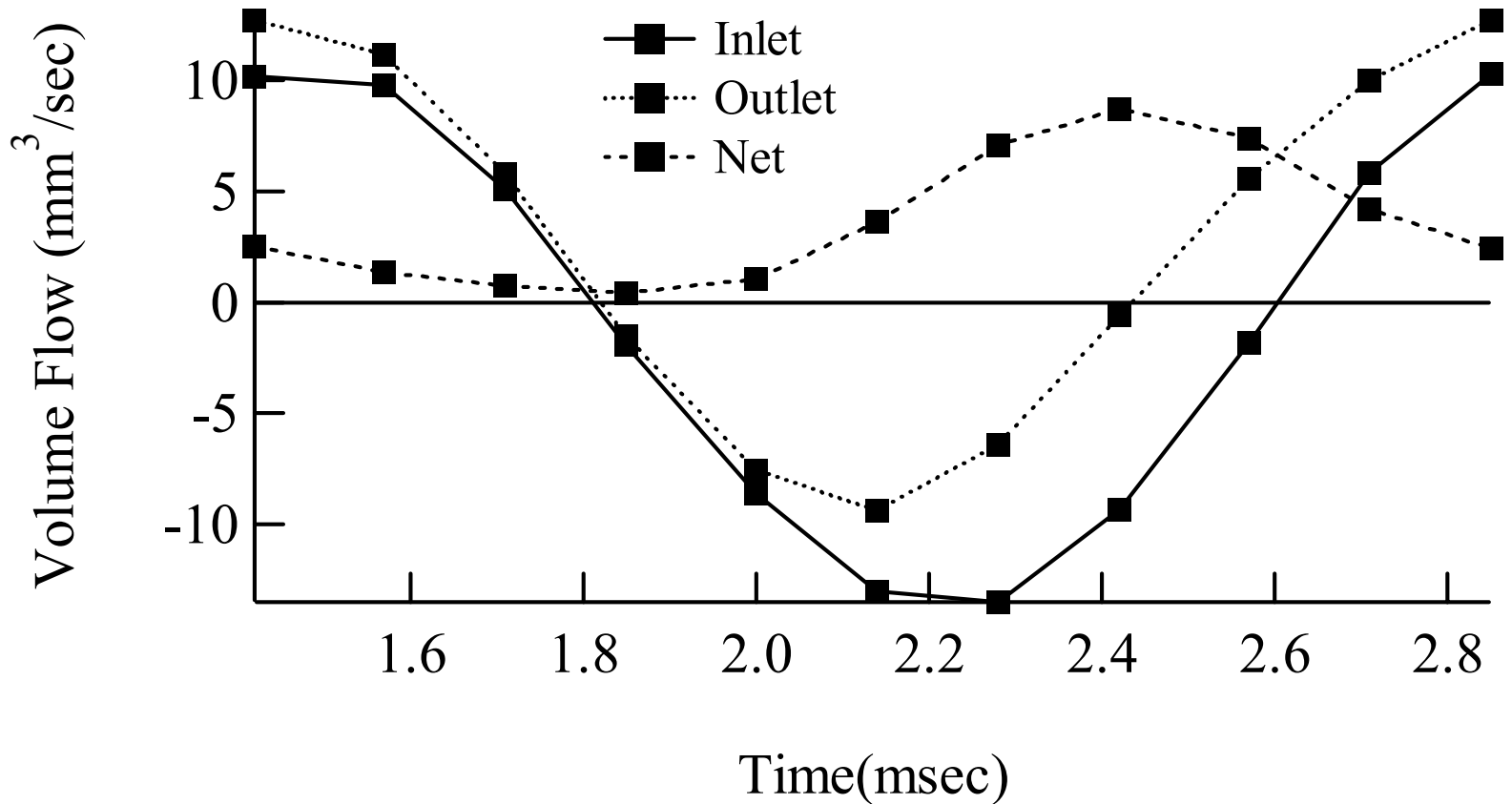
$$L_{\text{passages}} = 330 \mu\text{m}$$

$$W_{\text{inpassages}} = 66.7 \mu\text{m}$$

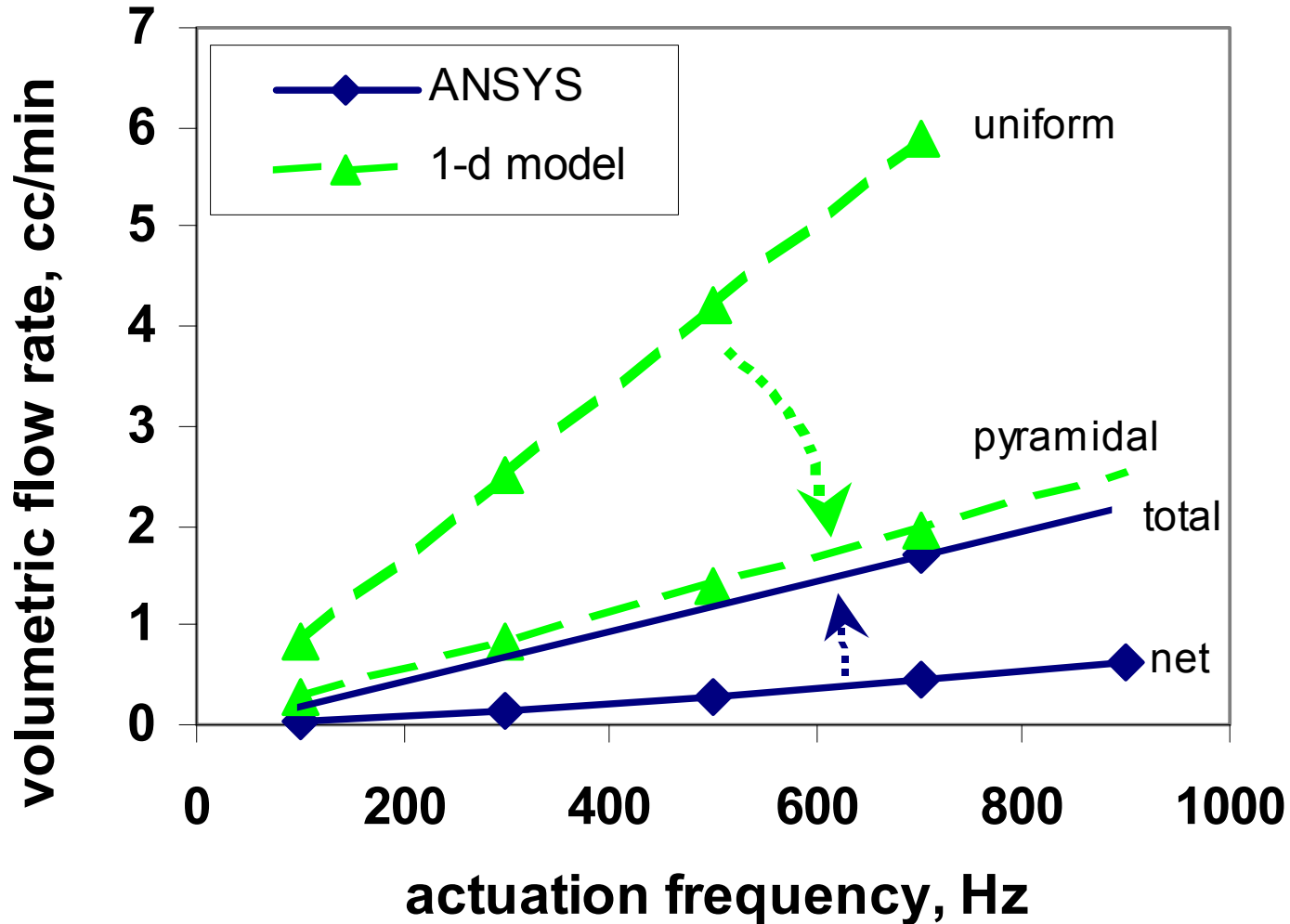
$$\alpha_{\text{valve}} = 5 \text{ degrees}$$

# ANSYS Results

(30um sinusoidal deflection at 700 Hz)



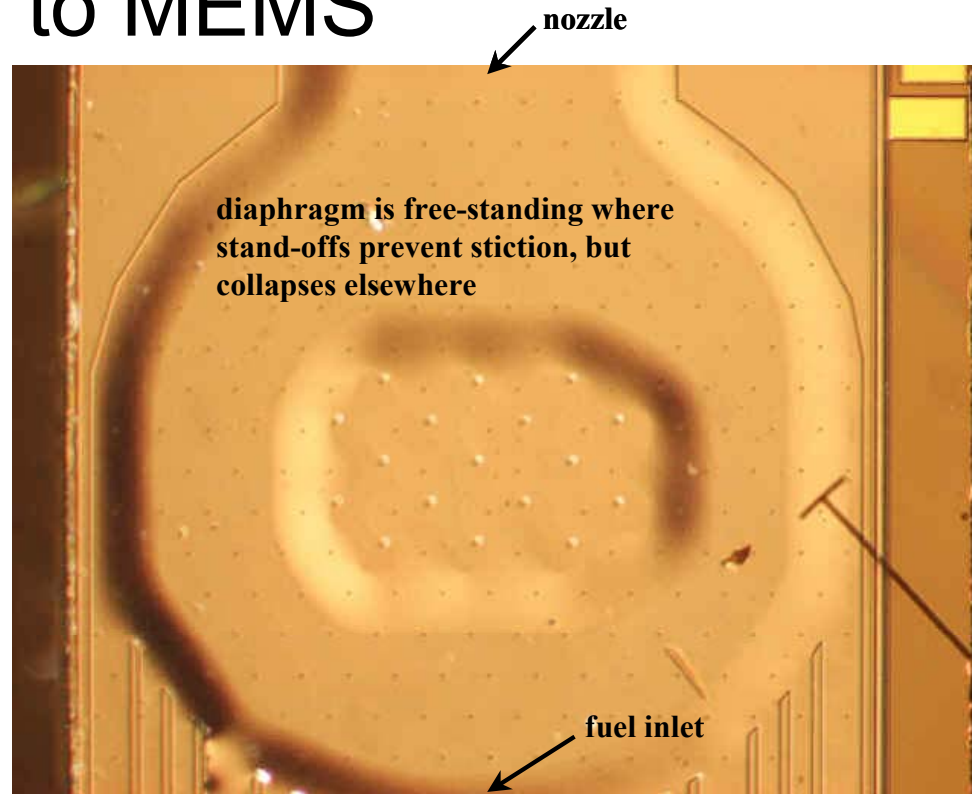
# Model Performance Predictions



# Stiction

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- Nemesis to MEMS



- Therefore, use Mastrangelo elastocapillary & peel numbers

# Materials

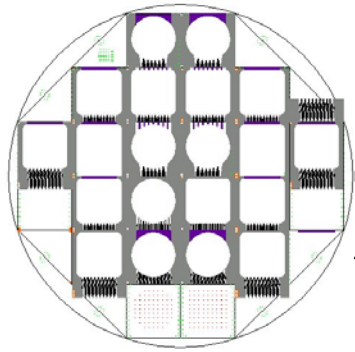
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- Silicon – most commonly used material
  - 3-inch SSP wafer costs about \$10
  - <1800°F
- Silicon carbide – 20X the cost, but good to 2900°F
- Silicon carbide nitride – also expensive, but highest temperature and strength

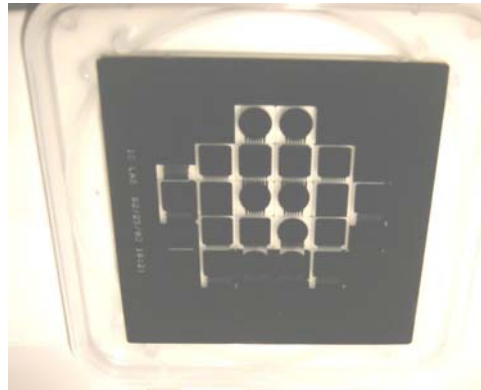


# Wafer Level Microprocessing

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CAD drawing



Mask



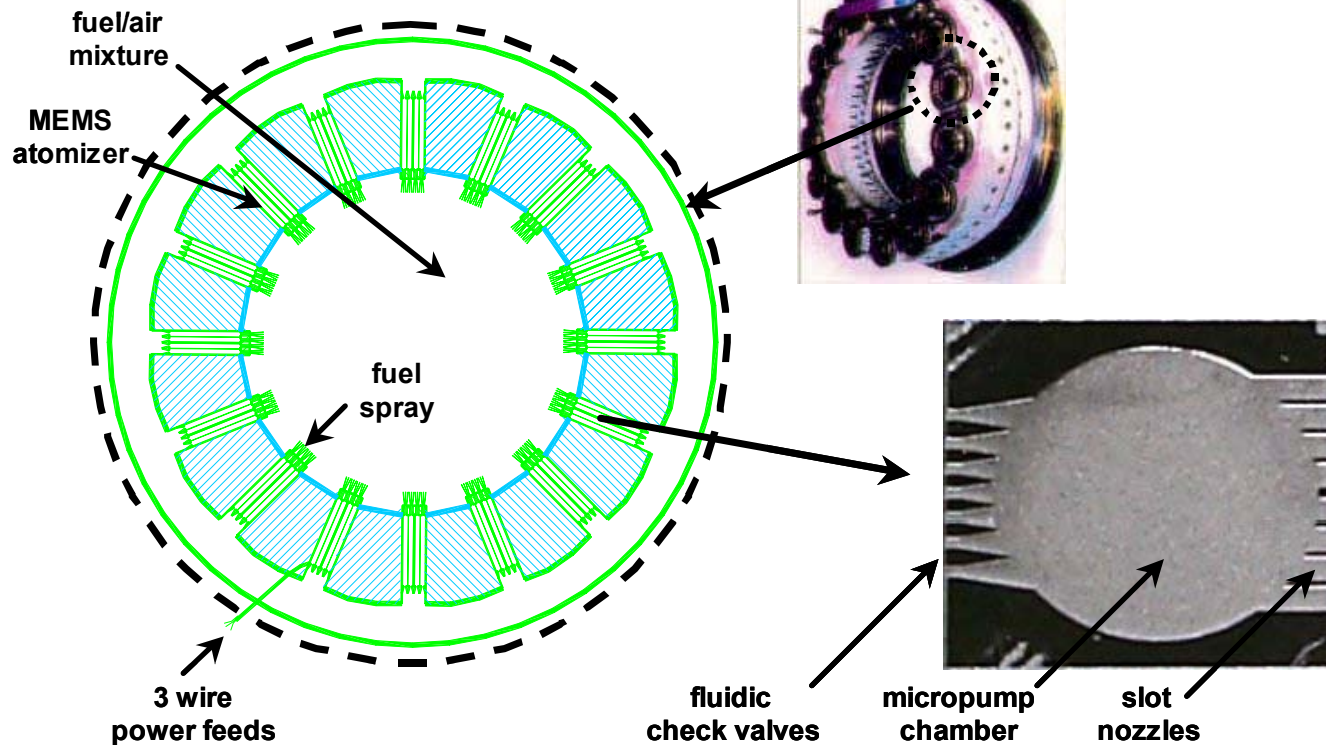
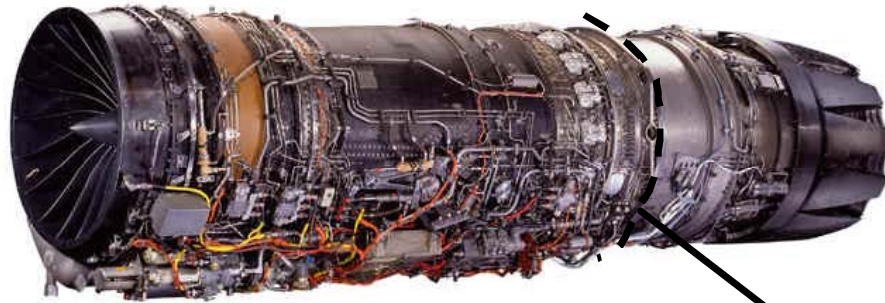
Pattern  
& etch

# Assembly & Packaging

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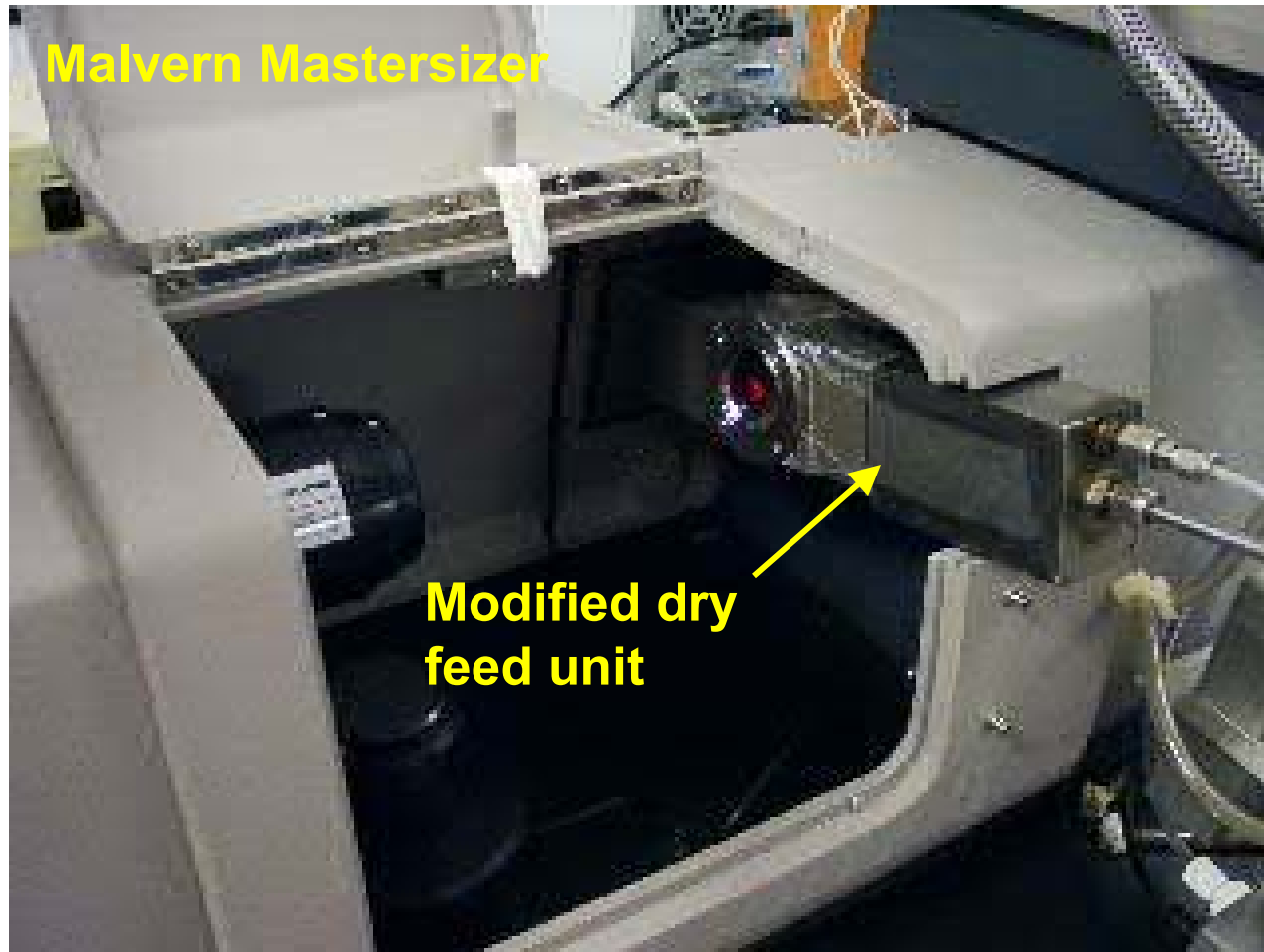


# Gas Turbine



# Test Setup

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# Conclusions

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- Analytical & computational tools Developed
- Design completed
- MEMS fabrication processes defined
- Atomizers built
- Testing underway

# Contact Info

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